

Quality is more than a word

ESPEC

TDDB Evaluation System

AMM-1000



Precise data acquisition Endless pursuit for reliability The Oxide Film Property Evaluation System

As wafer size is enlarged for mass production of high-density, high-function LSIs, reliability evaluation of oxide film is on increasing demand, which is key for LSI reliability. ESPEC'S TDDB Evaluation System will play an indispensable role for analyzing failure caused by pressure resistivity of thin insulation oxide film and characteristics and flattening of oxide film, at wafer, glass substrate, and package level.



MEASUREMENT EVALUATION SYSTEMS

CONDUCTOR RESISTANCE
EVALUATION SYSTEM

THROUGH-HOLE CONDUCTOR EVALUATION SYSTEM
SOLDER-JOINT CONTACT EVALUATION SYSTEM
BGA, CSP SOLDER JOINT CONTACT EVALUATION SYSTEM
CONNECTOR CONTACT RESISTANCE EVALUATION SYSTEM
FPC LIFE EVALUATION SYSTEM
OTHER INTERCONNECTION MATERIAL CONTACT
EVALUATION SYSTEM

ION MIGRATION EVALUATION SYSTEM

INSULATION RESISTANCE
EVALUATION SYSTEM

CAPACITOR INSULATION RESISTANCE EVALUATION SYSTEM
PCB, PWB INSULATION RESISTANCE EVALUATION SYSTEM
INSULATION RESISTANCE EVALUATION SYSTEM FOR
OTHER INSULATION MATERIAL

LOW-K INSULATION CHARACTERISTIC
EVALUATION SYSTEM

LEAK CURRENT MEASUREMENT SYSTEM

CAPACITOR LEAK CURRENT MEASUREMENT SYSTEM
FET LEAK CURRENT MEASUREMENT SYSTEM
SEMICONDUCTOR REVERSE BIAS LEAK CURRENT
MEASUREMENT SYSTEM

CAPACITOR TEMPERATURE
PROPERTY EVALUATION SYSTEM

LASER DIODE AGING SYSTEM

INTERCONNECTION MEASUREMENT
EVALUATION SYSTEM

CONNECTOR DISCONNECTION EVALUATION SYSTEM
SOLDER-JOINT DISCONNECTION EVALUATION SYSTEM
HARNESS CONTINUITY EVALUATION SYSTEM

ELECTRONICS PARTS ELECTRIC PROPERTY
AUTOMATIC EVALUATION SYSTEM

TEMPERATURE COMPENSATED CRYSTAL OSCILLATOR
TEMPERATURE PROPERTY TEST SYSTEM

OPTICAL COMPONENT
ENVIRONMENTAL TEST SYSTEM

ELECTRO-MIGRATION EVALUATION SYSTEM

LSI ELECTRO-MIGRATION EVALUATION SYSTEM
GMR HEAD ELECTRO-MIGRATION EVALUATION SYSTEM
GMR HEAD ELECTRO-MIGRATION RH EVALUATION SYSTEM
HIGH FREQUENCY ELECTRO-MIGRATION EVALUATION SYSTEM
WAFER LEVEL
PACKAGE LEVEL

TDDB EVALUATION SYSTEM

SEMICONDUCTOR PARAMETER
AUTOMATIC EVALUATION SYSTEM

FET(HOT-CARRIER) PROPERTY EVALUATION SYSTEM
TRANSISTOR PROPERTY EVALUATION SYSTEM

COMBINED ENVIRONMENTAL TESTING,
MEASUREMENT & EVALUATION SYSTEM

AUTOMATED RESONANCE POINT
SEARCH & MEASUREMENT SYSTEM

Performance



Prober for LCD

APPLICATIONS

TDDDB evaluation system

Package level
Wafer level (for 8 inch wafer, 12 inch wafer)

FET(Individual transistor) property evaluation system

Package level
Wafer level (for 8 inch wafer, 12 inch wafer)

Semiconductor, Liquid crystal glass substrate, etc..



Connection

● System configuration to fit number of measurement

Equipped with DC Multi Source Measurement (MSM) on each channel, which enable monitoring and output of voltage and current. MSM consists of 4 channels per board. The basic 40-channel configuration stores up to 10 boards. The system can be upgraded according to measurement volume and condition up to 5 units (200 MSMs).

● Precise current and voltage application measurement

Current at 9 ranges, measurement resolution of maximum current $\pm 100\text{mA}$, and minimum current $\pm 1\text{pA}$. Voltage at 2 ranges, resolution of maximum voltage $\pm 50\text{V}$ and minimum voltage 1mV . Enables a wide range and precise application and measurement.

● Measurement at minimum 10msec

Delivers high-speed measurement for multiple channels. Measures at top speed of 10msec per 40 channels, while acquiring data.

● Various evaluation items

The TDDDB Evaluation System is configured for wafer level and liquid crystal glass substrate level, by effectively systemizing MSM. It also applies for requirements of QDB evaluation and TZDB evaluation, while FET property evaluation can also be realized by exchanging software.

● Output by CSV file

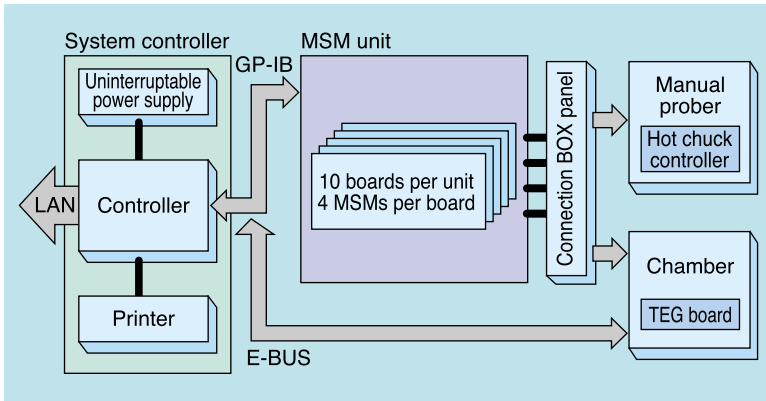
Automatic compilation of CSV file enable output by normal plotting. (Spread sheet software Microsoft EXCEL data can also be converted)

● LAN compatible

● Expansion to high-voltage load

To upgrade the system, we provide MSM boards designed specifically for a maximum + 100V high-voltage load.

SYSTEM BLOCK DIAGRAM



Uninterruptable power supply
Backup power supply for controller (Does not reset automatically when power restored)

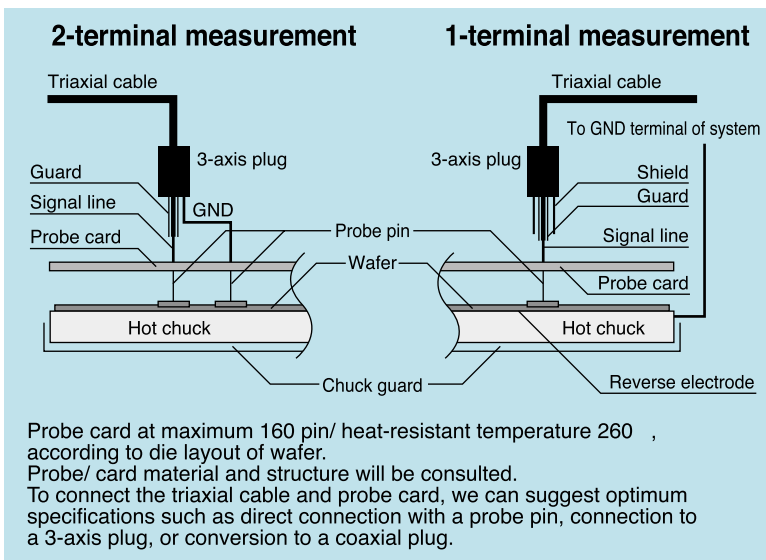
MSM unit
Incorporates 40ch MSMs per unit (maximum 5 units)

Connection BOX panel
Can be set as panel for prober shield BOX.
Triaxial cable
Connects specimen and MSM to reduce noise level.

Chamber
Evaluation at package level of specimen, under high temperature, using the TEG board.

E-BUS
Temperature control, monitor, alarm control of chamber with a GP-IB adapter.

CONNECTION TO A PROBER



Prober
Type1
Wafer level prober
For both 5 inch type and 8 inch type
Compatible with 300mm wafer type full automatic prober

Type2
Liquid crystal glass substrate (maximum 500 x 400mm)

Hot chuck
Compatible prober :
maximum 300 for wafer level
maximum 150 for liquid crystal glass substrate.

Probe card
We offer optimum probe card to meet required specification and layout such as number of channels, pins and wafer size. Enables whole contact with a single shot.

SPECIFICATION

Model		AMM-1000										
Software		Windows® 2000										
Voltage/current application range		- 50V to + 50V/ - 100mA to + 100mA										
Resolution		1mV step/ 1pA step										
Voltage/current measurement range		- 50V to + 50V/ - 100mA to + 100mA										
No. of measurement channels		Standard 40ch. Max. installment 200ch										
Measurement sampling speed		Short mode: 0 to 100msec 10msec interval 100msec to 10sec 100msec interval Over 10sec according to time table below Data acquisition without averaging										
		Medium mode: 0 to 100msec 20msec interval 100msec to 10sec 100msec interval Over 10sec according to time table below Averaging per 1 cycle										
Measurement sampling speed		Long mode: 0 to 10sec 100msec interval Over 10sec according to time table below Averaging per 5 cycle										
		<table border="1"> <thead> <tr> <th>Time table</th> <th>Measurement interval</th> </tr> </thead> <tbody> <tr> <td>10[sec] ~ 100[sec]</td> <td>1[sec] x multiply by 1, 2, 5 or 10</td> </tr> <tr> <td>100[sec] ~ 1000[sec]</td> <td>10[sec] x multiply by 1, 2, 5 or 10</td> </tr> <tr> <td>1000[sec] ~ 10000[sec]</td> <td>100[sec] x multiply by 1, 2, 5 or 10</td> </tr> <tr> <td>10000[sec] ~ 100000[sec]</td> <td>1000[sec] x multiply by 1, 2, 5 or 10</td> </tr> <tr> <td>100000[sec] ~ 1000000[sec]</td> <td>10000[sec] x multiply by 1, 2, 5 or 10</td> </tr> </tbody> </table>	Time table	Measurement interval	10[sec] ~ 100[sec]	1[sec] x multiply by 1, 2, 5 or 10	100[sec] ~ 1000[sec]	10[sec] x multiply by 1, 2, 5 or 10	1000[sec] ~ 10000[sec]	100[sec] x multiply by 1, 2, 5 or 10	10000[sec] ~ 100000[sec]	1000[sec] x multiply by 1, 2, 5 or 10
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External dimension	MSM unit	650W x 1300H x 800Dmm										
	System controller	570W x 1100H x 900Dmm										
Required utility		100V AC ± 10% 50/60Hz 15A										
		100V AC ± 10% 50/60Hz 50A										

● MSM Simplex Performance

Voltage range	Resolution	Accuracy	Max. current
± 10V	1mV	± (0.2% + 10mV)	100mA
± 50V	10mV	± (0.2% + 50mV)	

Voltage range	Resolution	Accuracy	Max. current
± 100mA	100μA	± (0.5% + 100μA + 2μA × Vo)	50V
± 10mA	10μA	± (0.5% + 10μA + 200nA × Vo)	
± 1mA	1μA	± (0.5% + 1μA + 20nA × Vo)	
± 100μA	100nA	± (0.5% + 100nA + 2nA × Vo)	
± 10μA	10nA	± (1.0% + 10nA + 200pA × Vo)	
± 1μA	1nA	± (1.0% + 1nA + 20pA × Vo)	
± 100nA	100pA	± (10% + 100pA + 2pA × Vo)	
± 10nA	10pA	± (2.0% + 10pA + 200fA × Vo)	
± 1nA	1pA	± (2.0% + 1pA + 20fA × Vo)	

Accuracy: ± (set value or % of specified value) ± (offset), Vo: output voltage (V)

Option

Wafer prober (8 inch, 12 inch)
8 inch

Prober external dimension	Manual prober	750W x 1500H x 800Dmm
	Semi auto prober	1100W x 1600H x 900Dmm
	Full auto prober	1000W x 1200H x 1000Dmm
Temperature range	MAX + 300	Resolution 1 step
Required utility	200V AC ± 10% 50/60Hz 30A x 1	

*Please contact us for details of 12 inch prober.

Prober for liquid crystal

Prober card

*Utility for prober differs according to type of prober.
We can coordinate your system accordingly.

Chamber

Chamber external dimension	750W x 1500H x 800Dmm	
Temperature range	MAX + 250	Resolution 1 step
Required utility	200V AC ± 10% 50/60Hz 20A x 1	

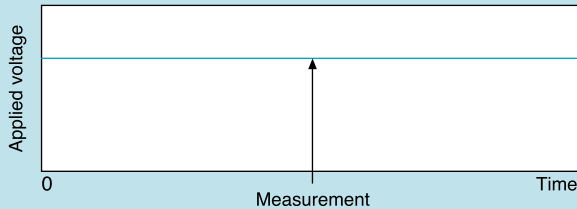
Applied voltage, + 100V Specification

EVALUATION PROCEDURES

Execute test by selecting from the following measurement mode library.

Fixed Voltage Measurement Mode

Measured with fixed voltage stress. The measurement current and breakdown time are stored.



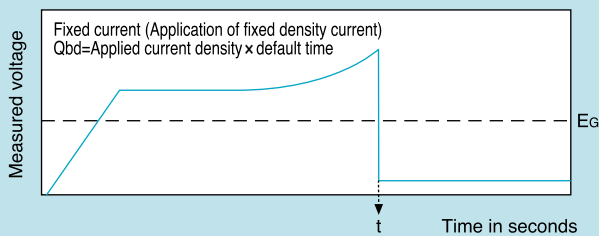
Soft Breakdown Mode

Measured by changing stress voltage and measurement voltage. The voltage measurement can be adjusted in 5 steps.



Current Stress Measurement

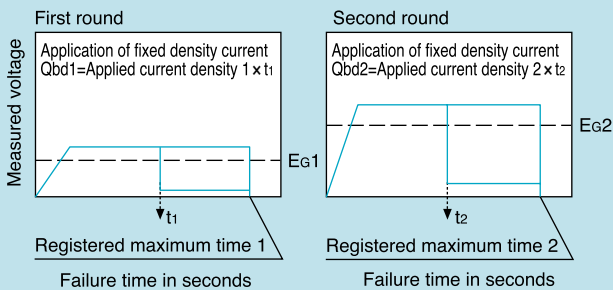
Voltage is measured by applying fixed current. The default time is recorded and stored.



Considered as breakdown when ratio of two continuous measurement value is above ΔEG electric field strength ratio.

Two-Step Current Stress Measurement

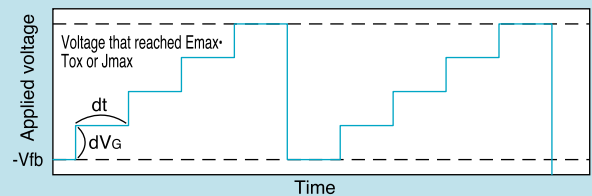
Different fixed current is applied two times (When breakdown does not occur the first time, the second test round is started)



Considered as breakdown when ratio of two continuous measurement value at both rounds is above ΔEG electric field strength ratio for both the first and second rounds.

Step Voltage Measurement (I-V characteristics measurement, TZDB method)

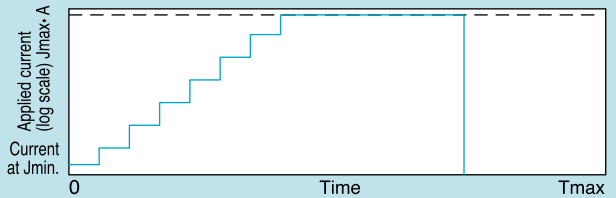
Measures the current at each voltage level while increasing voltage application stepwise.



Step Current Measurement (TZDB)

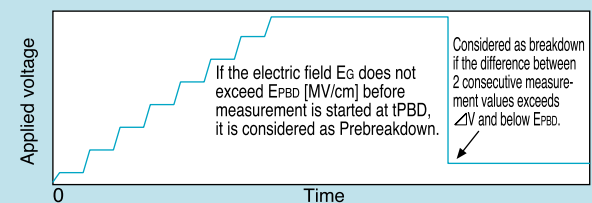
Measures time dependent change of voltage while increasing current application stepwise.

Test is terminated if a failure is detected.



Measurement is terminated if no breakdown is detected within Tmax.

Sample Measurement Data



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ISO 14001 (JIS Q 14001)
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